

HK-6

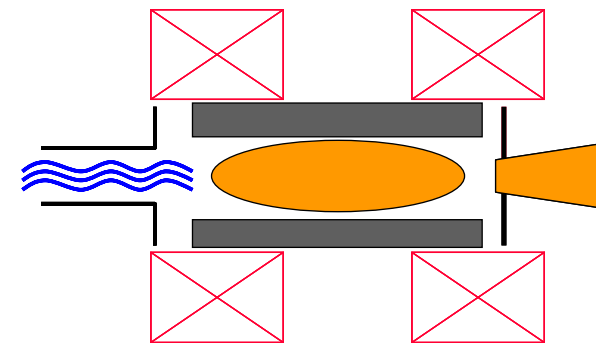
Oliver Kester

Overview

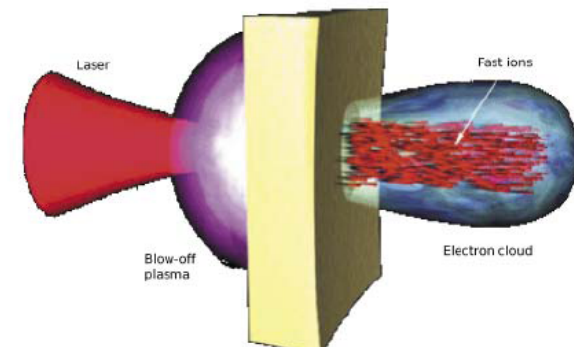
Ion source development:

- High charge state ion sources (ECRIS) Simulations (HK-6-2), Extraction and beam transport, Correction of x,y coupling (HK-6-3)
- High current rf proton-source development (no slide)
- Laser driven p-beams with TNSA (HK-6-1)

Electron Cyclotron Resonance Ion Source



TNSA (Target Normal Sheath Acceleration)



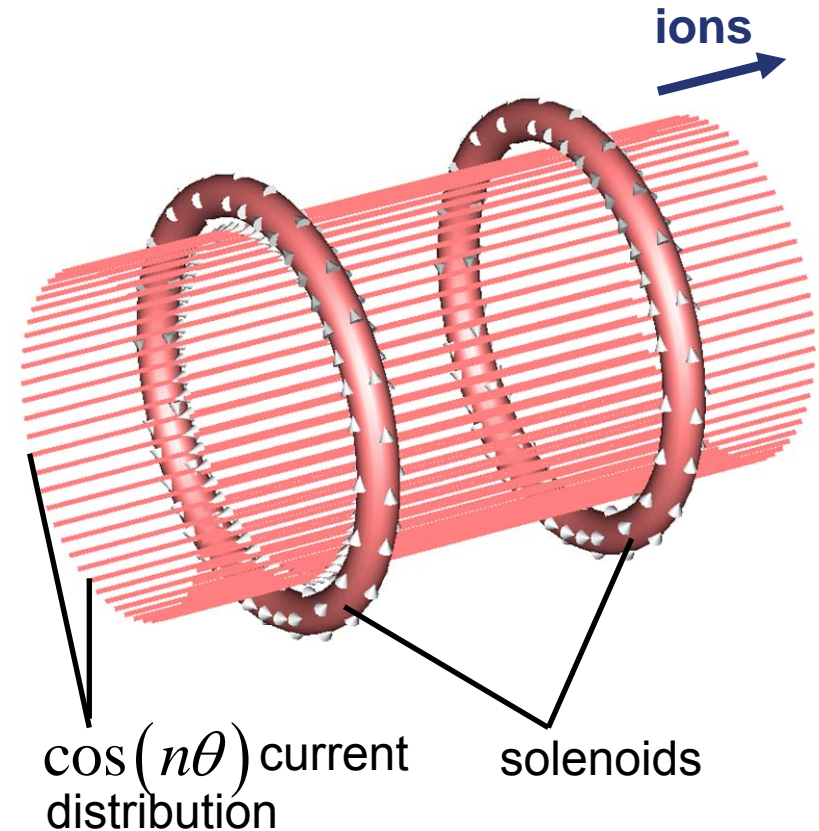
Simulations for ECR Sources

▪ Heavy Ion Source:

- Magnetic particle trap
- Solenoidal + multipole fields

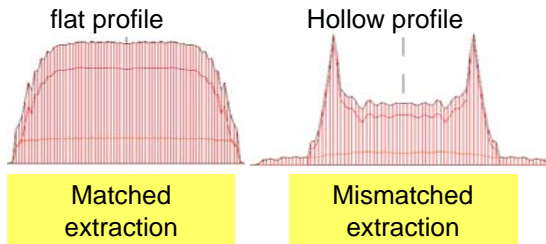
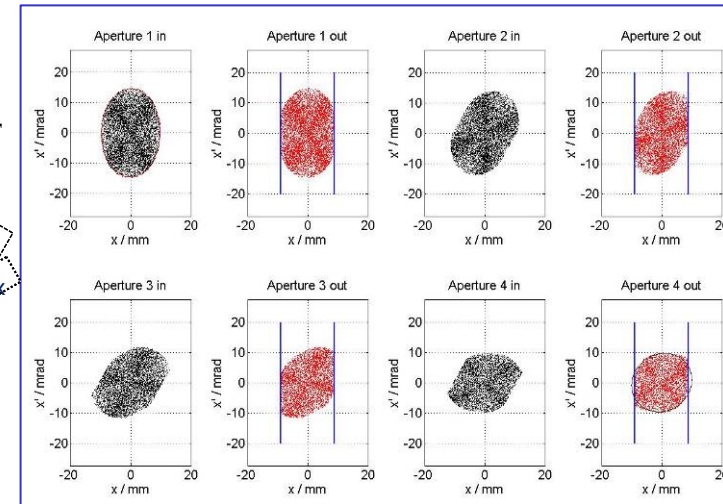
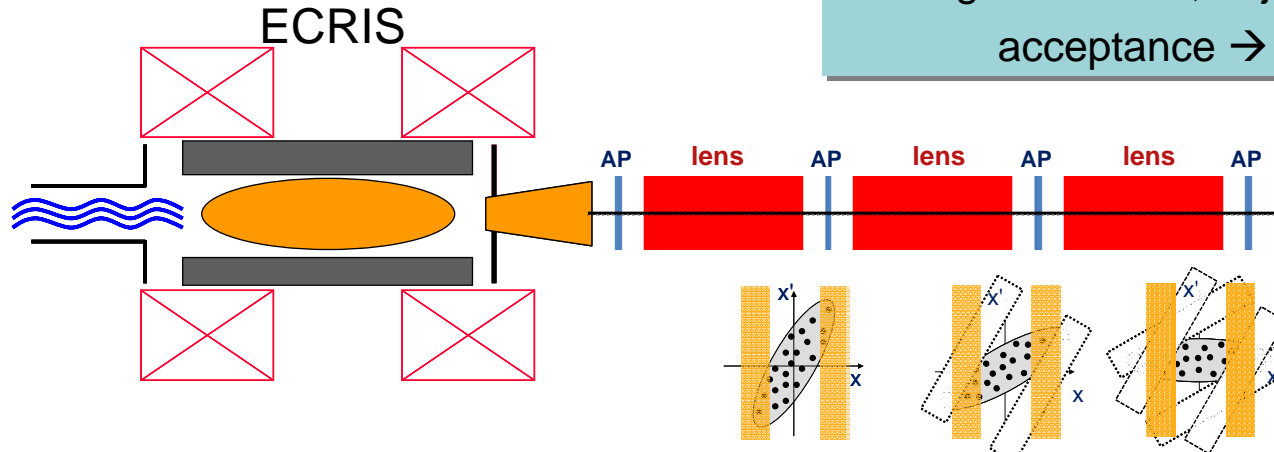
▪ Simulations:

- Setup of current coils
- (static) field distribution
- Determination of magnetic mirror ratio $\frac{B_{\max}}{B_{\min}}$
- Particle tracking

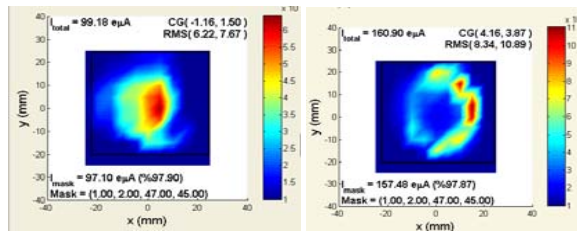


Transport and manipulation of beams from ECR ion sources

Cutting beam halo, adjustment of channel acceptance → tuning tool



x,y-Coupling due to solenoid field
→ Compensation with skew quads



$$\epsilon_{4D} = \det \Sigma_{4D} = \begin{vmatrix} \Sigma_{xx} & \Sigma_{xy} \\ \Sigma_{yx} & \Sigma_{yy} \end{vmatrix}$$

